

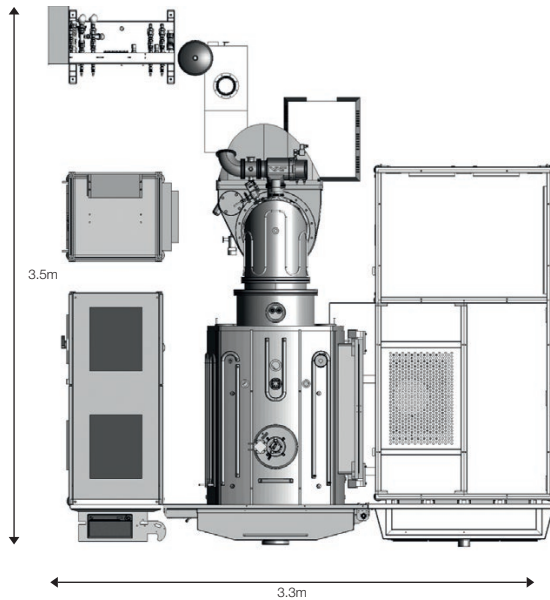


BAK AUTOLOAD

For superior wafer handling

BAK AUTOLOAD

Typical layout for BAK 761 with AUTOLOAD in standard configuration without optional load lock chamber.



With cassette to cassette handling for wafer sizes up to 8 inch, **BAK AUTOLOAD** completely eliminates manual handling of wafers saving time, eliminating operator errors and reducing costs. **BAK AUTOLOAD** takes care of all necessary steps including wafer alignment for flat or notch, preloading domes and complete dome exchange through a side port in the coater. For applications demanding even higher throughputs an optional vacuum load lock chamber can also be integrated. Whatever configuration you choose, precise control of robot and handling environment avoids potential sources of damage or contamination. Full integration with Evatec's KHAN process controller ensures seamless hardware management.

COMPLETE PROCESS CONTROL

- Full tracking of wafer position in the coating dome for highest traceability and statistical process control
- Automatic recognition and handling of metrology or dummy wafers
- Integration of bespoke post-treatment modules
- Dome exchange typically less than 3 minutes (standard configuration)

SUBSTRATE CAPACITY CHART

Wafer size	Dome Capacity
4"	42
6"	20
8"	9



Front end cassette load and unload



Precise handling of wafer by robot



Dome loading including metrology wafers



Dome transfer through dedicated side port



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